

207.2 Optical Microscope Linewidth Measurement (photomask)

SRMs 475 and 476 are for use in calibrating optical microscopes that measure the widths of opaque lines and clear spaces on integrated circuit photomasks used in semiconductor fabrication. They can also be used to calibrate line spacings and line-to-space ratios. They are not for use with partially transmitting materials, in reflected light with opaque materials, or in a scanning electron microscope. SRM 475 is patterned with antireflecting chromium on quartz; SRM 476 is patterned with bright chromium on glass.

For further information see SP 260-129, SP 260-119, SP 260-117 and 260-114

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PLEASE NOTE: The tables are presented to facilitate comparisons among a family of materials to help customers select the best SRM for their needs. For specific values and uncertainties, the certificate is the only official source.

SRM	Description	Linewidth (μm)	Pitch (μm)	Unit Size (cm)
475	Linewidth Measurement Standard	0.9 to 10.8	2 to 38	$6.35 \times 6.35 \times 0.15$
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